



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

S. TAKECHI et al.

Art Unit: 1752

Serial No. 10/024,373

Examiner: R.E. Ashton

Filed: December 21, 2001

Attorney Docket No.: 108077-00001

For: RADIATION SENSITIVE MATERIAL AND METHOD FOR FORMING PATTERN

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RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
Washington, D.C. 20231

Date: July 14, 2003

Sir:

This paper is filed in response to the Restriction Requirement dated May 13, 2003, in connection with the above-identified patent application. The period for responding is extended by the attached petition.